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(54) Title: MODULAR ELECTRONICS FOR FLOW CONTROL

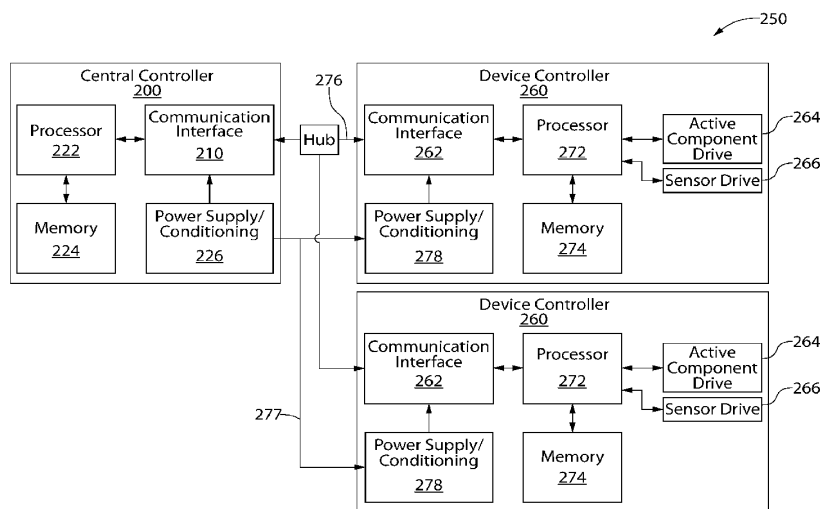


FIG. 4

(57) Abstract: Systems for manufacturing semiconductors are essential to enabling modern technologies. Such systems may include a central controller, a plurality of fluid supplies, a plurality of apparatus for controlling flow, and a processing chamber. The central controller may have a processor, a memory, and a communication module. The plurality of apparatus for controlling flow may have a device controller having an active component, a sensor, and a communication module. The communication may have a communication module, a memory, a sensor drive circuit operably coupled to the sensor, and an active component drive operably coupled to the active component. The central controller is configured to receive sensor data from the sensors of the plurality of apparatus for controlling flow and transmit active component commands to the active component drives of the device controllers to control the plurality of apparatus for controlling flow.

[Continued on next page]

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